



Sheet 1 of 1

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE										ATTY. DOCKET NO. 2146/41506/1	SERIAL NO. 10/718,435			
INFORMATION DISCLOSURE STATEMENT BY APPLICANT										APPLICANT: Arutiun Papken Ehlasarlan et al.				
(Use several sheets if necessary)										FILING DATE: November 20, 2003	GROUP Not yet assigned			
U.S. PATENT DOCUMENTS														
EXAMINER INITIAL	DOCUMENT NUMBER								DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
<i>pm</i>	6	2	9	6	7	4	2	10/2/2001	Kouznetsov	204	192	12		
<i>pm</i>	6	0	3	3	7	3	4	3/7/2000	Muenz et al.	421	309			
<i>pm</i>	5	3	0	6	4	0	7	4/26/1994	Hauzer et al.	204	192	34		
/														
FOREIGN PATENT DOCUMENTS														
	DOCUMENT NUMBER								DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION	
												YES	NO	
<i>pm</i>	DE	1	0	1	2	4	7	4	9	11/28/2002	Germany			X
<i>pm</i>	EP	1	2	6	0	6	0	3	11/27/2002	Europe				
/														
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)														
<i>pm</i>		Munz, W.-D., "Nouvelles tendances en procedes magnetron et arc", Le Vide, No. 297, Vol. 3/4, 2000, p. 205-223.												
<i>pm</i>		Munz, W.-D., "Wear Resistant PVD Coatings for High Temperature (950°C) Applications", SVC 42 nd Annual Conference, Chicago, April 17-22, 1999, p. 350-356.												
<i>pm</i>		Schonjahn, C., Donohue, L.A., Lewis, D.B., and Munz, W.-D., "Enhanced adhesion through local epitaxy of transition-metal nitride coatings on ferritic steel promoted by metal ion etching in a combined cathodic arc/unbalanced magnetron deposition system", Journal of Vacuum Science and Technology, Vol. 18, Issue 4, 2000, p. 1718-1723.												
<i>pm</i>		Munz, W.-D., Smith, I.J., Lewis, D.B., and Creasey, S., "Droplet formation on steel substrates during cathodic steered arc metal ion etching", Vacuum, Vol. 48, Issue 5, 1997, p. 473-481.												
<i>pm</i>		Wang, H.W., Slack, M.M., Lyon, S.B., Hovsepian, P., and Munz, W.-D., "The corrosion behaviour of macroparticle defects in arc bond-sputtered Cr/NbN superlattice coatings", Surface and Coatings Technology, Vol. 126, 2000, p. 279-287.												
<i>pm</i>		Ehlasarlan, A.P., New, R., Munz, W.-D., Hultman, L., Helmersson, U., and Kouznetsov, V., "Influence of high power densities on the composition of pulsed magnetron plasmas", Vacuum, Vol. 65, 2002, p. 147-154.												
EXAMINER <i>Robert McBeauld</i> DATE CONSIDERED <i>8/15/05</i>														
*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.														

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